

論 文

(1) テラ光情報処理・伝送システム

a . 時空間テラ光情報変換・伝送システムの研究開発

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b . 高速パターン識別光システムの研究開発

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(2) 高機能光学素子作製技術の確立

a . 2 次元超微細加工技術開発

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b . 3 次元微細光学素子作製技術の研究開発

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